

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Priority Application Serial No. 10/097,025
Priority Filing Date March 11, 2002
Inventor Trung Tri Doan et al.
Assignee Micron Technology, Inc.
Priority Group Art Unit 1763
Priority Examiner Karla A. Moore
Attorney Docket No. MI22-2471
Title: Atomic Layer Deposition Apparatus and Method

INFORMATION DISCLOSURE STATEMENT
PURSUANT TO 37 C.F.R. §§ 1.56, 1.97 AND 1.98


In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

The listed references were cited by, or submitted to, the Office in the parent, co-pending application of the above-identified application. The above-identified application is a divisional/continuation application of co-pending application Serial No. 10/097,025, filed March 11, 2002. Such prior disclosure is sufficient for the above-identified application as far as copies of the references are concerned. 37 C.F.R. § 1.98(d) and MPEP § 609(2).

Citation of these references is respectfully requested.

Respectfully submitted,

Dated 12-17-03

By: 
Mark S. Matkin
Reg. No. 32,268

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY. DOCKET NO. MI22-2471		SERIAL NO. PRIORITY 10/097,025	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)				APPLICANT: Micron Technology, Inc.			
				FILING DATE PRIORITY March 11, 2002		GROUP PRIORITY 1763	

U.S. PATENT DOCUMENTS							
*Examiner's Initials	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	4,793,283	12/1988	Sarkozy	118	725		
AB	5,000,225	03/1991	Murdoch	137	625.46		
AC	5,242,539	09/1993	Kumihashi et al.	216	67		
AD	5,286,296	02/1994	Sato et al.	118	719		
AE	5,607,510	03/1997	Makino et al.	118	723		
AF	5,746,581	05/1998	Okumura et al.	417	2		
AG	6,214,120	04/2001	Kim	118	719		
AH	6,306,247	10/2001	Lin	156	345.29		
AI	6,316,045	11/2001	Bernard et al.	427	8		

FOREIGN PATENT DOCUMENTS							
Document Number	Date	Country	Class	Subclass	Translation		
					Yes	No	
AJ	JP 62192582 A	08/1987	Japan				
AK	JP 02220367 A	09/1990	Japan				
AL	JP 06005520 A	01/1994	Japan				

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)			
	AM		
	AN		
	AO		

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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	AK							
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